

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

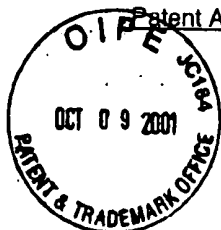
Patent Application

Inventor(s): Hubbard

Serial No.: 09/520,686

Filed: 3/7/00

Title: WAFER TARGET DESIGN AND METHOD FOR DETERMINING CENTROID OF WAFER TARGET



Group Art Unit: 2857

Examiner: ~~WALHUNBY~~
Not yet assigned

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Form 1449

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
<i>W</i>	A	4,253,112	2/24/81	Doemens	358	101	5/21/79
<i>W</i>	B	5,760,484	6/2/98	Lee et al.	257	797	2/11/97
<i>W</i>	C	4,880,309	11/14/89	Wanta	356	401	4/14/87
	D						
	E						
	F						
	G						
	H						
	I						

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation
	L						Yes No
	M						
	N						
	O						
	P						
	Q						
	R						

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
<i>W</i>	S	PATENT ABSTRACTS OF JAPAN, vol. 017, no. 272 (E-1371), 26 May 1993 (1993-05-26) - & JP 05 013306 A (Fujitsu Ltd), 22 January 1993 (1993-01-22) abstract; figures
	T	
Examiner	Date Considered	
<i>W</i>	5-15-04	

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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